
 FORM PTO-1449/A and B (Modified)
**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

Sheet	1	of	9
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APPLICATION NO.: 10/090,381	ATTY. DOCKET NO.: P00743/70003
FILING DATE: March 4, 2002	
APPLICANT: Stephen D. SENTURIA	
GROUP ART UNIT:	EXAMINER:

U.S. PATENT DOCUMENTS

Examiner's Initials #	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication or of issue of Cited Document MM-DD-YY
		Number	Kind Code		
<i>AS</i>		3,553,364		Lee	01/05/71
<i>AS</i>		4,234,788		Palmer et al.	11/18/80
<i>AS</i>		4,731,670		Allen et al.	03-15-1988
<i>AS</i>		4,805,038		Seligson	02-14-1989
<i>AS</i>		5,022,745		Zayhowski et al.	06/11/91
<i>AS</i>		5,115,344		Jaskie	05-19-1992
<i>AS</i>		5,164,688		Larson	11/17/92
<i>AS</i>		5,168,249		Larson	12/01/92
<i>AS</i>		5,175,521		Larson	12/29/92
<i>AS</i>		5,206,557		Bobbio	04/27/93
<i>AS</i>		5,212,582		Nelson Technology Center 2600	05/18/93
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<i>AS</i>		5,311,360		Bloom et al.	05-10-1994
<i>AS</i>		5,353,641		Tang	10/11/94

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		Office/ Country	Number	Kind Code			
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<i>AS</i>		WO	91/02991	A1		03-07-1991	

OTHER ART — NON PATENT LITERATURE DOCUMENTS

Examiner's Initials #	Cite No	Include name of the author (in CAPITAL LETTERS) title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue number(s), publisher, city and/or country where published.	Translation (Y/N)
<i>AS</i>		<u>MICROMECHANICAL LIGHT MODULATOR ARRAY FABRICATED ON SILICON</u> , K.E. PETERSEN, IBM Research Lab., Applied Physics Letters, Vol. 31, No. 8, 10/15/77, pp 521-523	

EXAMINER <i>ASellu</i>	DATE CONSIDERED <i>3/16/05</i>
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FORM PTO-159A and B (Modified)				APPLICATION NO.: 10/090,381		ATTY. DOCKET NO.: P00743/70003	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				FILING DATE: March 4, 2002			
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		Office/ Country	Number	Kind Code			
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		WO	01/11419	A2	Godil et al.	15-02-2001	--
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		<u>MINIATURE FABRY-PEROT INTERFEROMETERS MICROMACHINED IN SILICON FOR USE IN OPTICAL FIBER WDM SYSTEMS</u> , J.H. JERMAN et al., IEEE 1991 372, International Conf. On Solid-State Sensors and Actuators 1991, pp 372-375	

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		EP	1 143 287	A2		10-10-2001		

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		Solgaard et al., "Deformable grating optical modulator," <u>Optics Letters</u> , Vol. 17, No. 9, May 1, 1992, pgs. 688-690.	
		Goossen et al., "Silicon Modulator Based on Mechanically-Active Anti-Reflection Layer with 1 Mbit/sec Capability for Fiber-in-the-Loop Applications," <u>IEEE Photonics Technology Letters</u> , Vol. 6, No. 9, September 1994, pgs. 1119-1121.	
		<u>SPECTRALLY SELECTIVE GAS CELL FOR ELECTROOPTICAL INFRARED COMPACT MULTIGAS SENSOR</u> , MELENDEZ et al., Elsevier Science S.A., Sensors and Actuators 46-47 (1995) 417-421	
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<i>[Signature]</i>		<u>MOCRO-ACTUATED MIRRORS FOR BEAM STEERING</u> , GUSTAFSON et al., SPIE- Society of Photo-Optical Instrumentation Engineering, Vol. 3008, 1997, pp 90-99	
<i>[Signature]</i>		<u>DESIGNS TO IMPROVE POLYSILICON MICROMIRROR SURFACE TOPOLOGY</u> , BURNS et al., SPIE- Society of Photo-Optical Instrumentation Engineering, Vol. 3008, 1997, pp 100-110	
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		Number	Kind Code		
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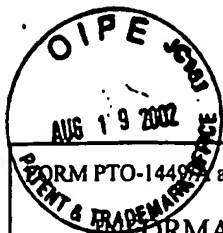
Examiner's Initials #	Cite No.	Include name of the author (in CAPITAL LETTERS) title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue number(s), publisher, city and/or country where published.	Translation (Y/N)
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		Number	Kind Code		
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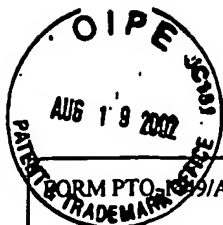
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FORM PTO-159/A and B (Modified)			APPLICATION NO.: 10/090,381	ATTY. DOCKET NO.: P00743/70003	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT			FILING DATE: March 4, 2002	RECEIVED AUG 21 2002	
			APPLICANT: Stephen D. SENTURIA		
Sheet	8	of	9	GROUP ART UNIT:	EXAMINER: Technology Center 2600

U.S. PATENT DOCUMENTS

Examiner's Initials #	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication or of issue of Cited Document MM-DD-YY
		Number	Kind Code		

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		Office/ Country	Number	Kind Code			

Examiner's Initials #	Cite No.	Include name of the author (in CAPITAL LETTERS) title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue number(s), publisher, city and/or country where published.	Translation (Y/N)
<i>AS</i>		Ford et al., "Dynamic Spectral Power Equalization Using Micro-Opto-Mechanics," <u>IEEE Photonics Technology Letters</u> , Vol. 10, No. 10, October 1998, pgs. 1440-1442.	
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<i>AS</i>		<u>SIMULATING ELECTROSTRICTIVE DEFORMABLE MIRRORS: II. NONLINEAR DYNAMIC ANALYSIS</u> , HOM, Lockheed Martin Missiles and Space, Smart Mater. Struct. 8, (1999), 07/26/99, 07/26/99	
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<i>AS</i>		<u>MODELING, DESIGN, FABRICATION AND MEASUREMENT OF A SINGLE LAYER POLYSILICON MICROMIRROR WITH INITIAL CURVATURE COMPENSATION</u> , MIN et al., Elsevier Science S.A., Sensors and Actuators 78 (1999) 8-17	
<i>AS</i>		<u>REAL TIME OPTICAL CORRECTION USING ELECTROSTATICALLY ACTUATED MEMS DEVICES</u> , HORENSTEIN, et al., Dept. of Aerospace and Mech. Eng., BU, Boston, MA, J. of Electrostatics, 1999, pp 69-81	
<i>AS</i>		<u>SURFACE MICROMACHINED SEGMENTED MIRRORS FOR ADAPTIVE OPTICS</u> , COWAN et al., IEEE J. of Selected Topics in Quantum Electronics, Vol. 5, No. 1, Jan/Feb. 1999, pp 90-101	
<i>AS</i>		<u>MICROELECTROMECHANICAL DEFORMABLE MIRRORS</u> , BIFANO et al., IEEE J. of Selected Topics in Quantum Electronics, Vol. 5, No. 1, Jan/Feb. 1999, pp 83-89	

EXAMINER <i>Asells</i>	DATE CONSIDERED <i>3/16/05</i>
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AUG 19 2002
PATENT OFFICE


FORM PTO 9/A and B (Modified) INFORMATION DISCLOSURE STATEMENT BY APPLICANT		APPLICATION NO.: 10/090,381 FILING DATE: March 4, 2002 APPLICANT: Stephen D. SENTURIA GROUP ART UNIT:	ATTY. DOCKET NO.: P00743/70003 RECEIVED AUG 21 2002 EXAMINER: Technology Center 2600
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U.S. PATENT DOCUMENTS					
Examiner's Initials #	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication or of issue of Cited Document MM-DD-YY
		Number	Kind Code		

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		Office/ Country	Number	Kind Code			

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		DESIGN AND FABRICATION OF 10X10 MICRO-SPATIAL LIGHT MODULATOR ARRAY FOR PHASE AND AMPLITUDE MODULATION, CHUNG et al., Sensors and Actuators 78, Elsevier Science S.A., 1999, pp 63-70	
		A DESIGN-BASED APPROACH TO PLANARIZATION IN MULTILAYER SURFACE MICROMACHINING, MALI et al., Dept. of Aerospace and Mech. Eng., BU, Boston, MA, Micromech. Microeng. 9 (1999) pp 294-299	
		VARIABLE GRATINGS FOR OPTICAL SWITCHING: RIGOROUS ELECTROMAGNETIC SIMULATION AND DESIGN, GANI et al., Opt. Eng. 38(3) 552-557, (March 1999) Soc. of Photo-Optical Ins. Eng. pp 552-557	
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		DEVELOPMENT OF MICROELECTROMECHANICAL DEFORMABLE MIRRORS FOR PHASE MODULATION OF LIGHT, MALI et al., Dept. of Aerospace and Mech. Eng., BU, Boston, MA, pp 542-548	
		MICRO-ELECTRO-MECHANICAL VARIABLE BALZE GRATINGS, BURNS et al., Air Force Institute of Technology, Dept. of Ele and Comp Eng., Wright-Patterson AFB, Ohio, pp 55-60	

EXAMINER: 	DATE CONSIDERED: 3/16/05
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FORM PTO-1449/A and B (Modified) INFORMATION DISCLOSURE STATEMENT BY APPLICANT		APPLICATION NO.: 10/090,381	ATTY. DOCKET NO.: P00743-78003005
		FILING DATE: March 4, 2002	CONFIRMATION NO.: 5189
		APPLICANT: Stephen D. Senturia.	
		GROUP ART UNIT: 2633	EXAMINER: Not Yet Assigned
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Examiner's Initials	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication or of issue of Cited Document MM-DD-YYYY
		Number	Kind Code		
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<i>AS</i>	2	6,141,139		Furlani et al.	10/31/2000
<i>AS</i>	3	6,108,117		Furlani et al.	08/22/2000
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<i>AS</i>	5	5,233,456		Nelson	08/03/1993
<i>AS</i>	6	5,202,785		Nelson	04/13/1993
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		Office/Country	Number	Kind Code			
<i>AS</i>	8	EP	1 014 143	A1	Eastman Kodak Company	June 28, 2000	

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Examiner's Initials	Cite No	Include name of the author (in CAPITAL LETTERS) title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue number(s), publisher, city and/or country where published.	Translation (Y/N)

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FORM PTO-1449/A and B (Modified)		APPLICATION NO.: 10/090,381	ATTY. DOCKET NO.: P00743.70003.US
INFORMATION DISCLOSURE STATEMENT BY APPLICANT 		FILING DATE: March 4, 2002	CONFIRMATION NO.: 5189
		APPLICANT: Stephen D. Senturia	
		GROUP ART UNIT: 2633	EXAMINER: Not Yet Assigned
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Examiner's Initials	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication or of issue of Cited Document MM-DD-YYYY
		Number	Kind Code		
<i>AB</i>	P1	5,212,582		Nelson	05-18-1993
<i>AB</i>	P2	5,392,151		Nelson	02-21-1995
<i>AB</i>	P3	6,072,620		Shiono et al.	06-06-2000
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<i>AB</i>	P8	6,636,658	B2	Goodman, et al.	10-21-2003
<i>AB</i>	P9	6,664,706		Hung, et al.	12-16-2003

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Examiner's Initials	Cite No.	Foreign Patent Document			Name of Patentee or Applicant of Cited Document (not necessary)	Date of Publication of Cited Document MM-DD-YYYY	Translation (Y/N)
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<i>AB</i>	P10	Copending patent application serial no. 09/975,169, filed on 10/11/2001 by Deutsch et al.		
<i>AB</i>	P11	Copending patent application serial no. 10/090,380, filed 03/04/2002 by Hung et al.		

EXAMINER <i>ABellu</i>	DATE CONSIDERED <i>3/16/05</i>
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